

# SSG Space Based Silicon Carbide Optical Systems



**SSG**  
Precision Optronics, Inc.

SSG SiC Overview – MSFC May 2002



# SSG Precision Optronics (SSGPO) Profile



Aerospace Engineering, Optical Fab & integration/Test



System Manufacturing Facility



Tinsley Laboratory



SiC Foundry

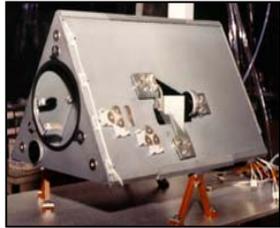
- 24 year old company specializing in major optical/mechanical and precision beam/motion control systems
  - National Asset, Major NASA Science, Advanced Technology Demos, tactical & commercial
  - Over 35 space & aircraft flight systems; many FFP
  - Over 50 Phase 2 SBIR grants - key technology enabler
  - >180 employees
- Commercial production supplier of precision optical/scanner product for 3D metrology markets
- >10 tactical ATD programs;

- World class technical & management staff
- Fully integrated computer design tools & major optical/LOS & vacuum test facilities
- >120,000 sq. ft. in 4 modern locations
- Team member with most US Aerospace instrument primes & Government Labs
- ISO 9001 Certified

**SSGPO's Growth Based on Unique Technologies, Solid Reputation & Successful Track Record Solving Tough Engineering Problems**

# SSG Fabricates Precision Opto-Mechanical Instruments in ALL Candidate Materials

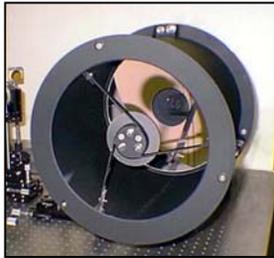
## SiC



NMP-DS1 MICAS



NMP/EO-1



Laser Comm

## Be



SBIRS-Lo/LADS Afocal

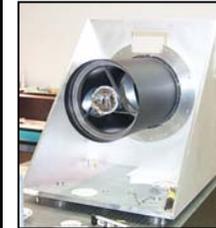


HIRDLS

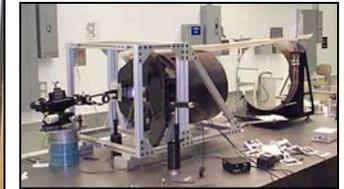


IR Telescope

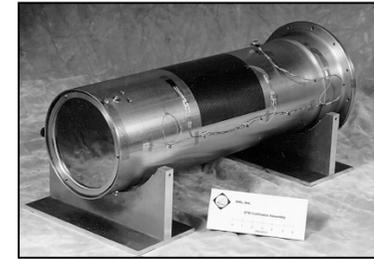
## Glass/GrCy



TRIANA

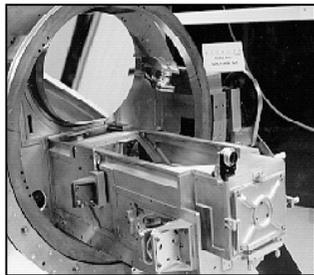


Orbview 3 Telescope

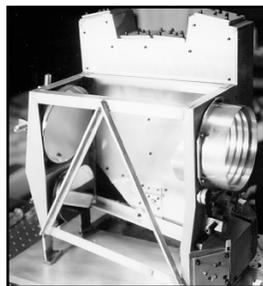


Cryo Refractor

## Al (w & wo Ni)



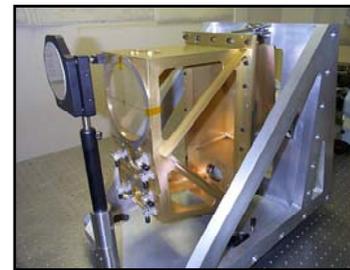
SPIRIT III MSX



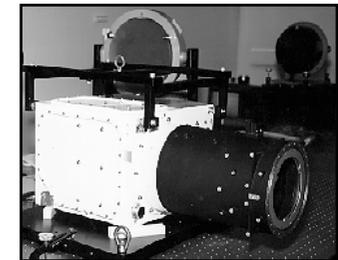
HSI/Lewis



KOMPSAT



Hyperion



SBV/MSX

Extensive experience designing, fabricating & testing with numerous materials allows us to take a systems approach on material selection, applying the right materials on an application by application basis

# SSG/Tinsley Recognized as a Premier Optical Manufacturing Resource

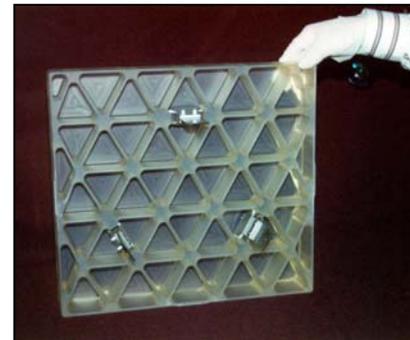
- SSG/Tinsley Laboratories recognized state-of-the-art aspheric optical manufacturing resource
  - Surface figures better than 5 nm pk-valley
  - Computer Controlled Optical Surfacing used to produce state-of-the-art optics in a fast, deterministic fashion



AMSD



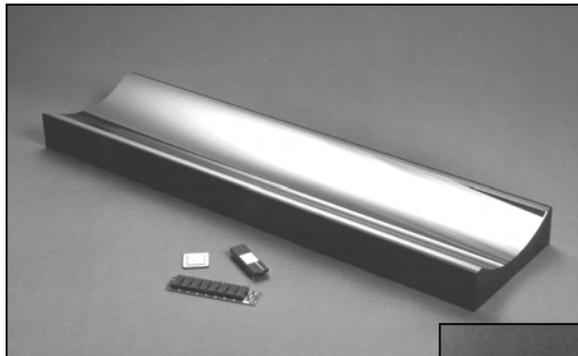
SIRTF



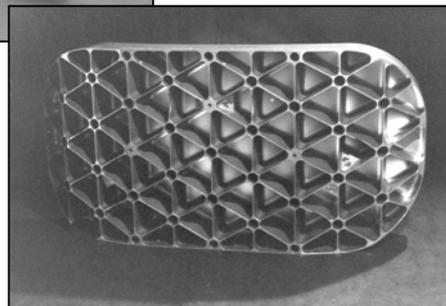
FUSE



Collimator



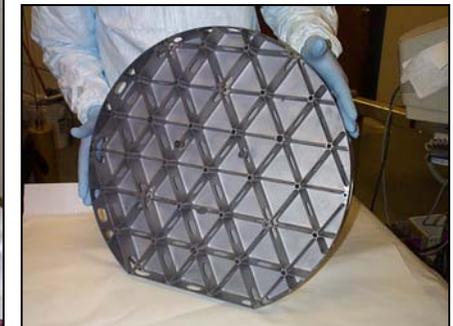
SiC X-Ray Toroidal Mirror



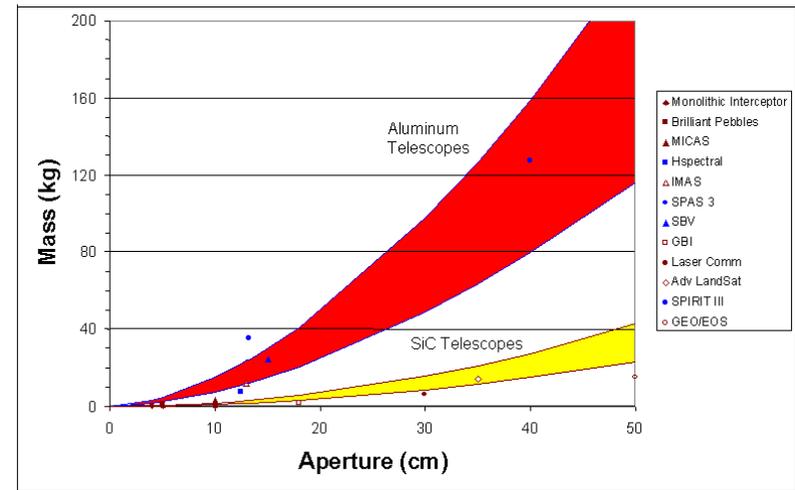
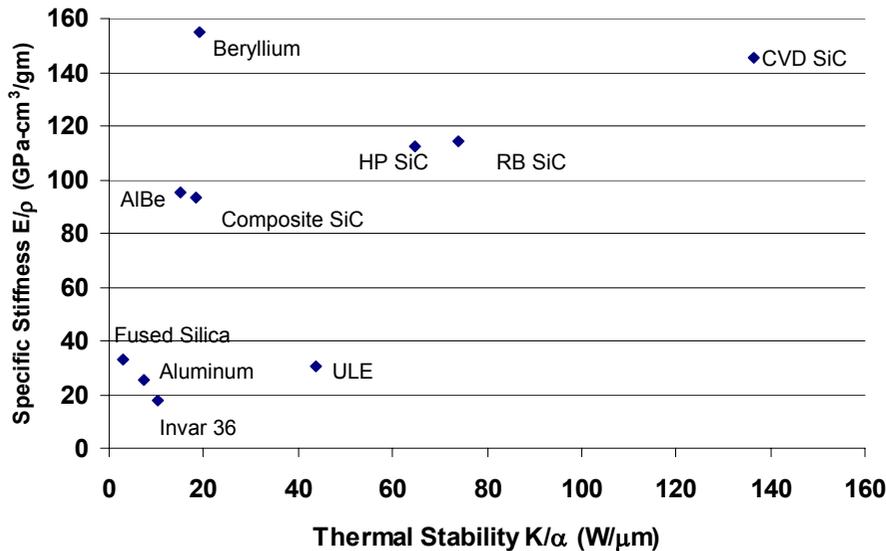
Lightweighted Beryllium Mirror



Subscale Be Mirror Demonstrator  
(0.5m Precursor to AMSD/NGST)



# Why Silicon Carbide for Space-based Optical Systems?



## SiC Offers:

- Lightweight features of Be
- Cryogenic optical performance of glass to visible/UV wavelengths
- Superior thermal stability to cryo temperatures (8x)
- Cost advantages of Al - lower potential production costs
- Fast delivery schedule due to inexpensive commercial processes

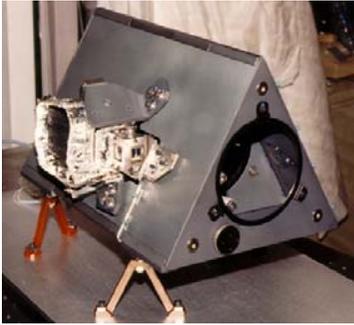
## Issues:

- Brittleness
- Attachments
- Scaling to larger sizes, esp. structures

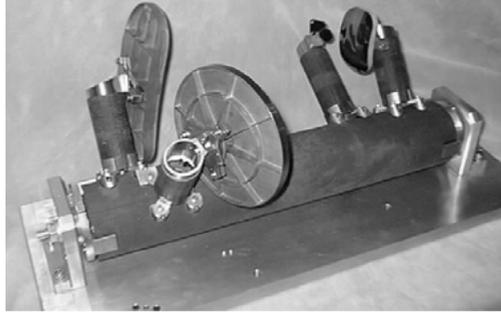
SiC only solution for very lightweight visible quality telescopes  
(2.5 to 3X lighter than glass)

SSG has hardware demonstrated solutions to mitigate SiC issues

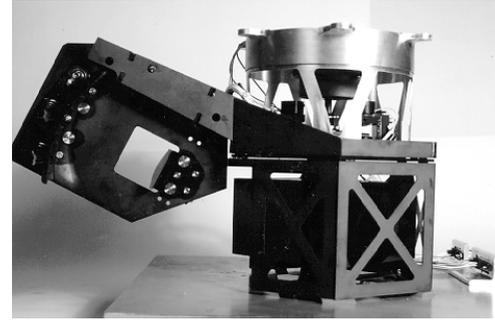
# SSG Is Industry Leader in SiC Telescope Systems



NMP DS-1/MICAS



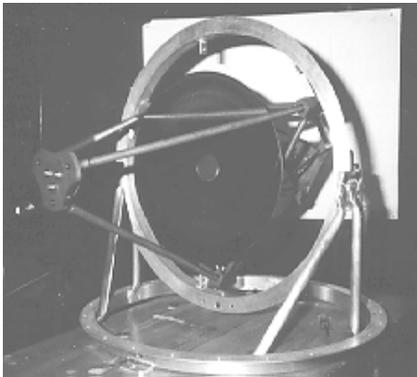
IMAS/NPOESS



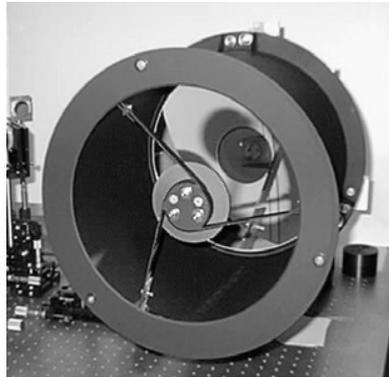
BP



Phased Array



0.5m GEO



LaserComm



NMP EO-1/ALI

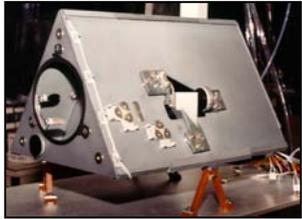


GBI

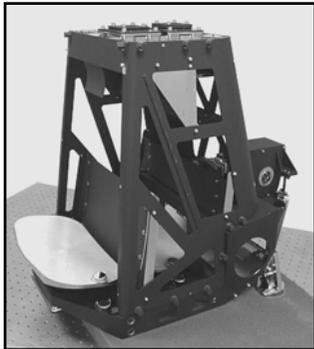
- SSG has extensive experience designing, manufacturing, integrating, aligning and testing SiC optical systems and opto-mechanical systems
- Numerous SBIR systems and technology demonstrations
- Two SiC flight systems

# SSG is Leading Supplier of SiC Systems and Components

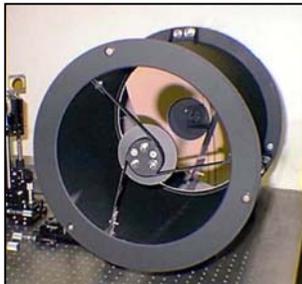
## Optical Systems



NASA DS-1 MICAS

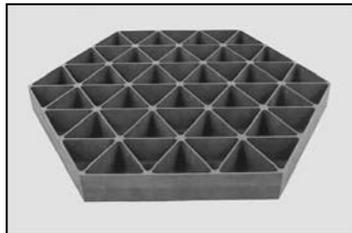


NASA EO-1 ALI



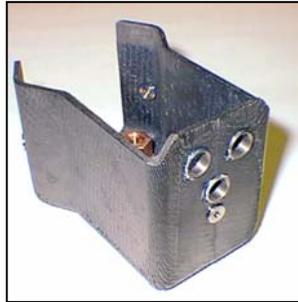
Lasercom Transceiver

## Mirrors



Aspheres and flats, light weight & thermally stable

## Structures



flight composite SiC components



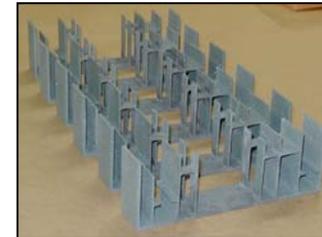
Optical benches in RB and composite SiC



## Components



Optical mounts

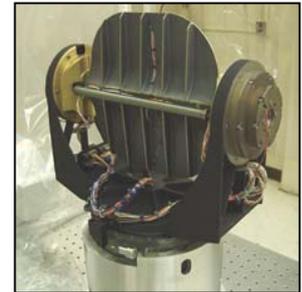


Lithography Components

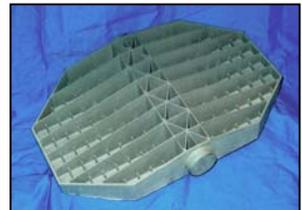
## Scan Mirrors



2-axis aircraft scan/stabilization



NASA's HIRDLS scanner



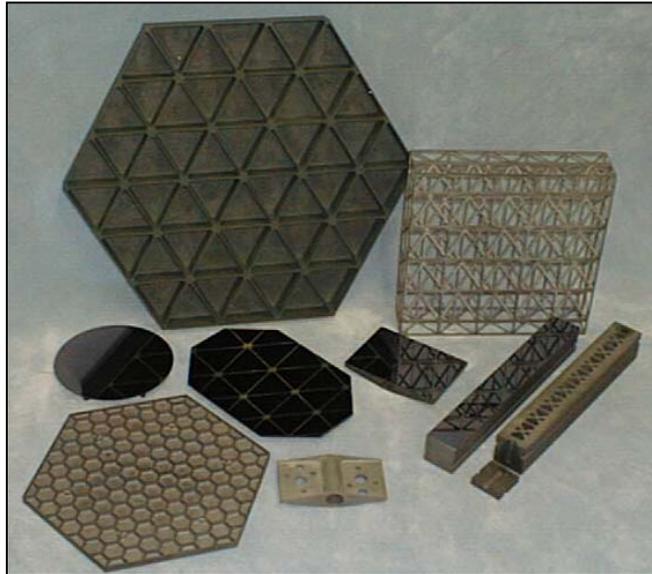
GIFTS scan mirror



**SSG**  
Precision Optonics, Inc.



## SiC - Materials Selection



### Reaction Bonded (RB) SiC

- Suitable for optical surfaces
  - High specific stiffness (~80% the specific stiffness of Be; 2x better than carbon/GrEp)
  - Excellent thermal conductivity (4x better than carbon/GrEp)
  - Excellent polishability to optical tolerances

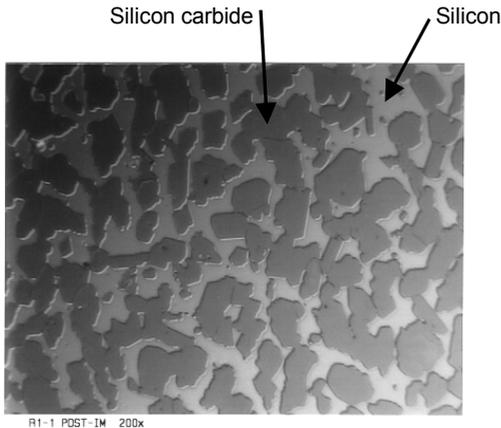


### Fiber Reinforced Composite SiC

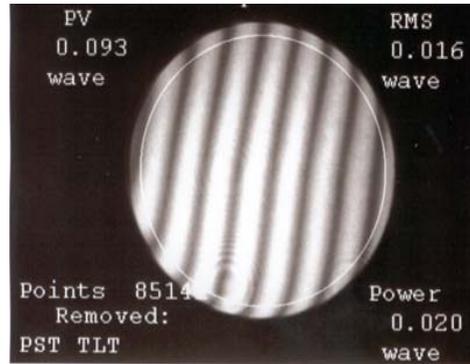
- Optimized for structural applications
  - Excellent fracture toughness or damping (2x better than carbon/GrEp; 20x better than Be)
  - Both SiC materials can be combined to exploit the advantages of each
  - Both have no problems with anisotropic material properties of CME

Several Proprietary forms of SiC developed to address the specific needs of high precision optics/structures

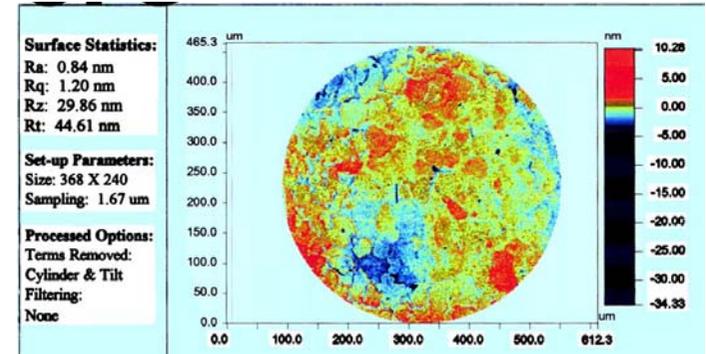
# Optical Properties – RB Silicon Carbide



RB SiC Microstructure

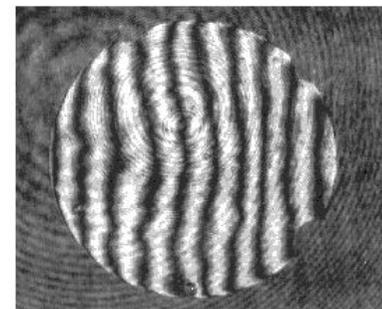
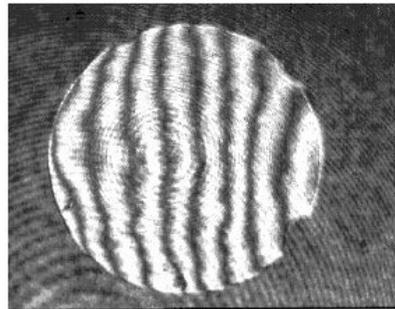


Excellent Polishability  
 (< 0.1 waves pk-valley @ 0.6 um)



Excellent Surface Finish  
 (< 13 Angstroms RMS)

T = 135 K  
 Pk-valley WFE = 0.53  $\lambda$   
 RMS WFE = 0.08  $\lambda$

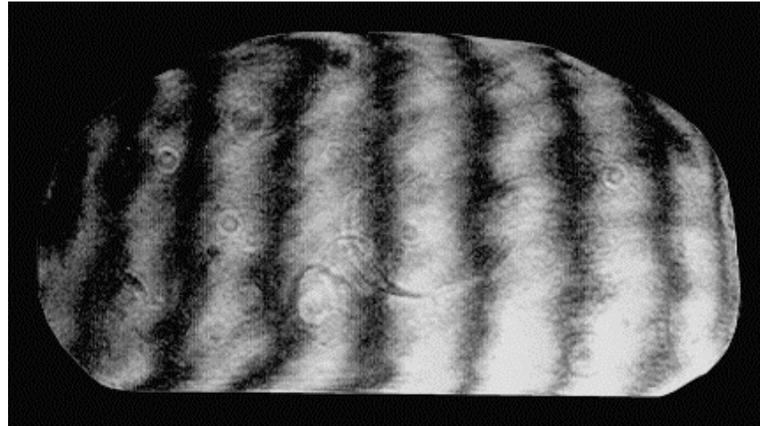


T = 295 K  
 Pk-valley WFE = 0.47  $\lambda$   
 RMS WFE = 0.08  $\lambda$

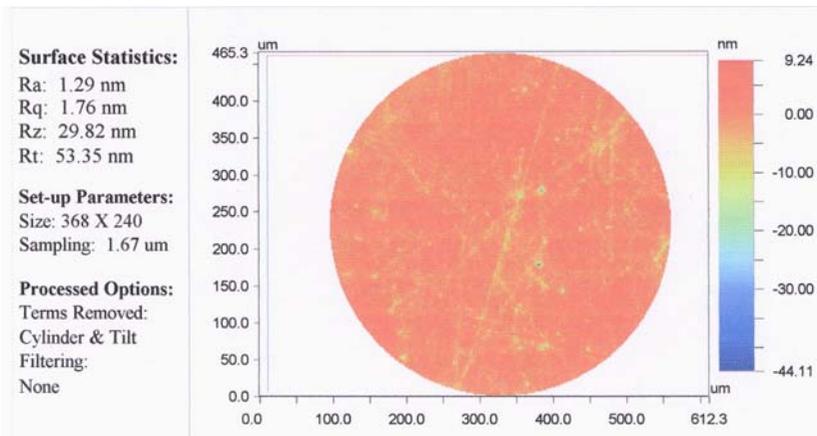
Excellent stability down to cryogenic temperatures

- RB SiC demonstrated to have excellent optical properties
  - Surface figure, finish and cryogenic stability demonstrated at the component and the system level

## Optical Properties – Silicon coated Silicon Carbide



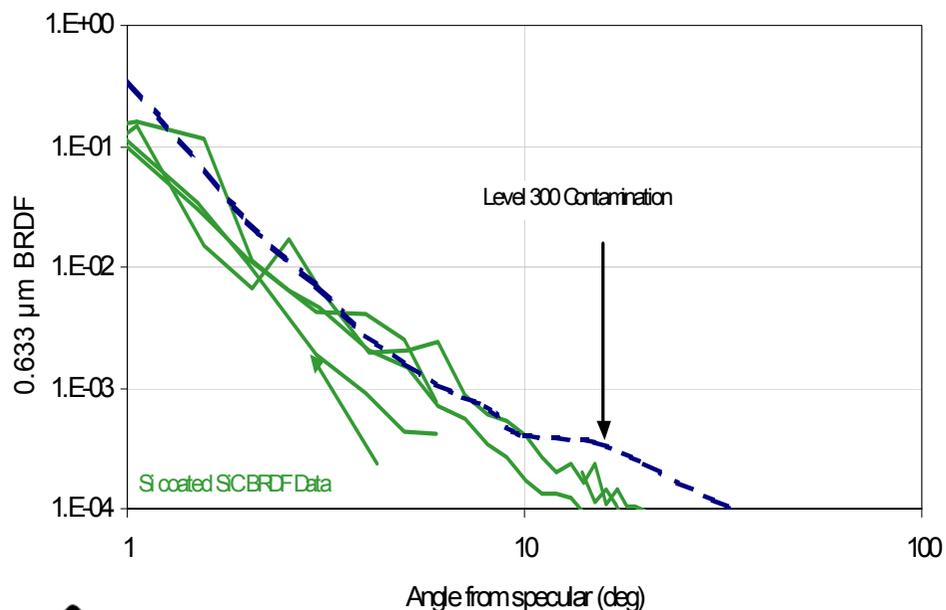
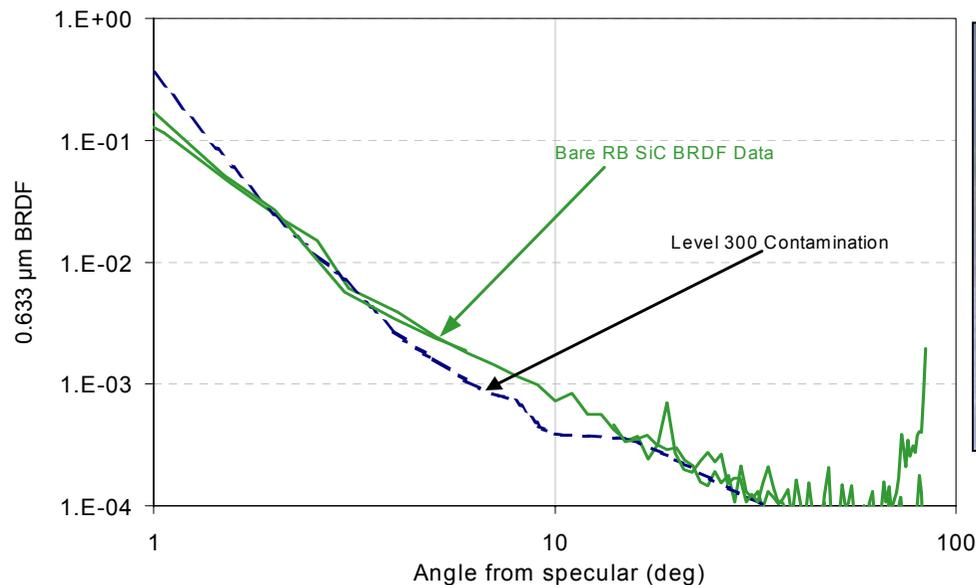
Excellent Polishability  
(< 0.25 waves pk-valley @ 0.6 um)



Excellent Surface Finish (< 18 Angstroms RMS)

- Silicon cladding somewhat compromises the surface finish achievable with the aspheric optics
- Silicon cladding has no negative effect on surface figure achievable
- Thermal stability depends on the thickness of the silicon cladding and the stiffness of the SiC mirror substrate

# Stray Light Characteristics of SiC



## Component BRDF Performance

- SSG has done extensive work to optimize the SiC manufacturing polishing process to ensure optimal stray light performance of SiC optics
- Component BRDF demonstrated to be consistent with level 300 contamination

# CVD SiC Coated RB SiC Optics

Talystep at Naval Air Warfare Center  
China Lake, California 93555

August 2, 2000

Stylus: ETI-13, 0.8  $\mu\text{m}$  radius; 1 mg loading

Profile lengths: 1000  $\mu\text{m}$  (1 mm); 31  $\mu\text{m}/\text{sec}$  stylus speed; 2658 Data Points; Gain 8  
100  $\mu\text{m}$ ; 3.1  $\mu\text{m}/\text{sec}$  stylus speed; 2658 Data Points; Gain 9

Data stored on Dell Computer at C:\taly\tdata\

20.3°C; 60 % RH; 0.49  $\text{\AA}$  rms instrument noise



## 1000 $\mu\text{m}$ profile length

SSG\_1 1.01  $\text{\AA}$  rms; 8.00  $\text{\AA}$  PV  
SSG\_3 1.73  $\text{\AA}$  rms; 9.40  $\text{\AA}$  PV  
SSG\_5 0.92  $\text{\AA}$  rms; 8.00  $\text{\AA}$  PV  
SSG\_7 1.14  $\text{\AA}$  rms; 9.00  $\text{\AA}$  PV

Average 1.20  $\pm$  0.26  $\text{\AA}$  rms

8.60  $\pm$  0.60  $\text{\AA}$  PV

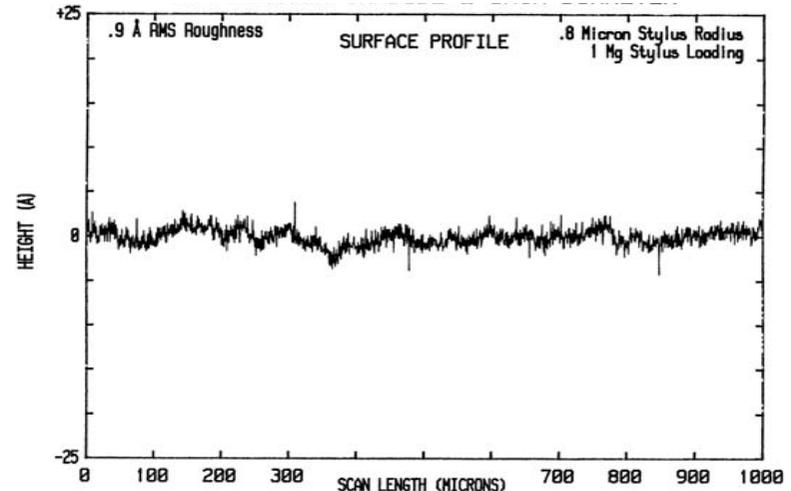
## 100 $\mu\text{m}$ profile length

SSG\_2 0.83  $\text{\AA}$  rms; 7.4  $\text{\AA}$  PV  
SSG\_4 0.82  $\text{\AA}$  rms; 5.4  $\text{\AA}$  PV  
SSG\_6 0.72  $\text{\AA}$  rms; 5.0  $\text{\AA}$  PV  
SSG\_8 0.78  $\text{\AA}$  rms; 7.7  $\text{\AA}$  PV

Average 0.79  $\pm$  0.04  $\text{\AA}$  rms

6.40  $\pm$  1.2  $\text{\AA}$  PV

Multiple Pieces demonstrated with Surface  
Finishes ranging from 0.7 – 1.4 Angstroms RMS

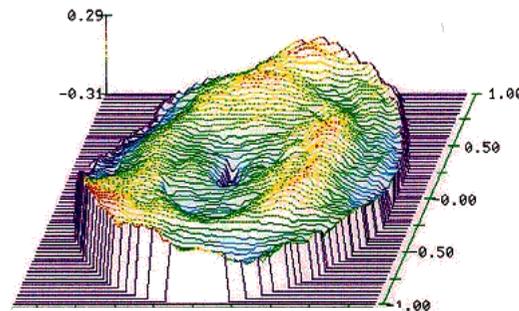
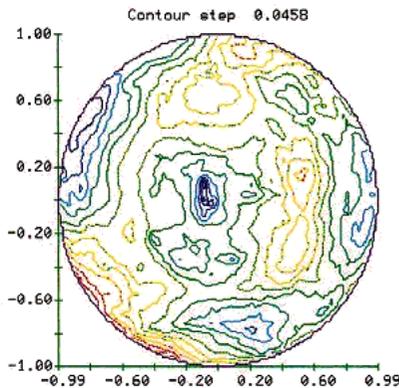
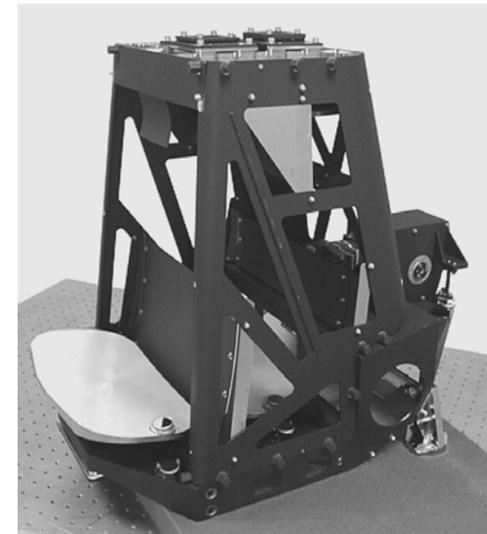
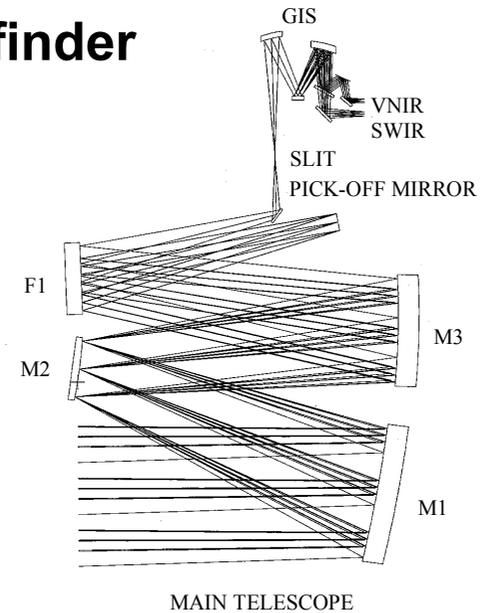


- Work has been done in CVD SiC coating RB SiC optics in order to improve surface finish capabilities

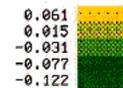
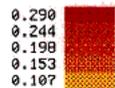
# NMP EO-1 Advanced Landsat Pathfinder

## Description

- 12.5 cm aperture; 45 cm mirrors
- 15 degree FOV VIS/IR imager partially populated with multicolor FPA modules
- SiC/Si telescope mirrors with invar structure
- Temperature range 0 deg  $\pm$ 50 deg C
- Structural pallet/enclosure/kinematic mounts
- In-flight calibration
- Weight: 40 kg.
- Delta launch



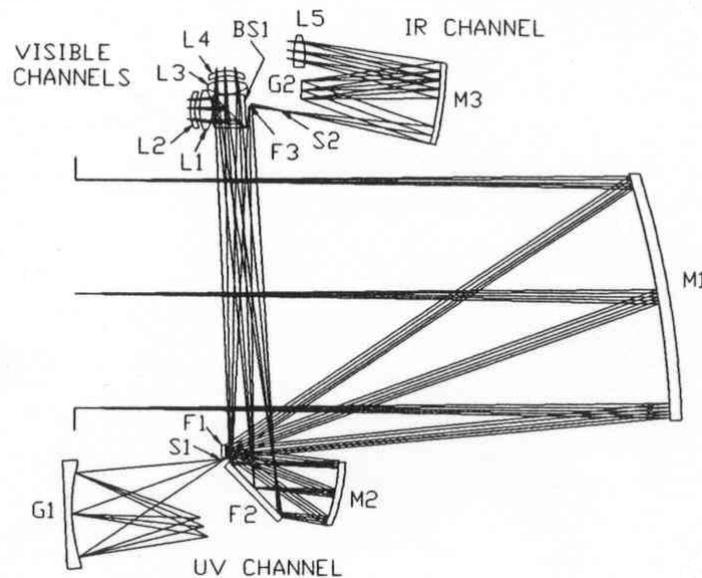
**On-axis Field Point**  
 $.596\lambda$  P-V       $.083\lambda$  RMS



**NMP Earth Orbiter 1st Mission is co-flying with  
LandSat 7 demonstrating SiC based technology**

# NMP DS-1

## Miniature Infrared Camera and Spectrometer (MICAS)



Temperature	System Wavefront Error (Pk-Valley)	System Wavefront Error (RMS)
293 K	0.70 $\lambda$	0.13 $\lambda$
136 K	0.79 $\lambda$	0.16 $\lambda$

Results of the MICAS Thermal Vacuum Testing (@ $\lambda = 0.633 \mu\text{m}$ )

### Description

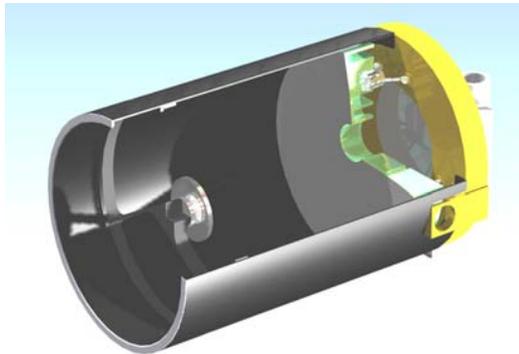
- 10 cm aperture;
- All SiC instrument
- Two visible imaging channels, IR spectrometer, and UV spectrometer combined
- System demonstrated excellent thermal stability down to cryogenic temperatures
- Weight: 2.8 kg.

**NMP DS-1 Mission successfully completed, MICAS used for primary science data collection and navigation**

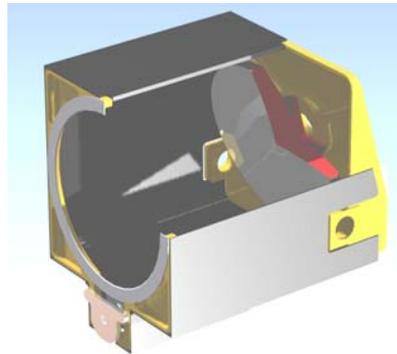
# LaserCOMM & GEO Applications

## Telescope Concepts

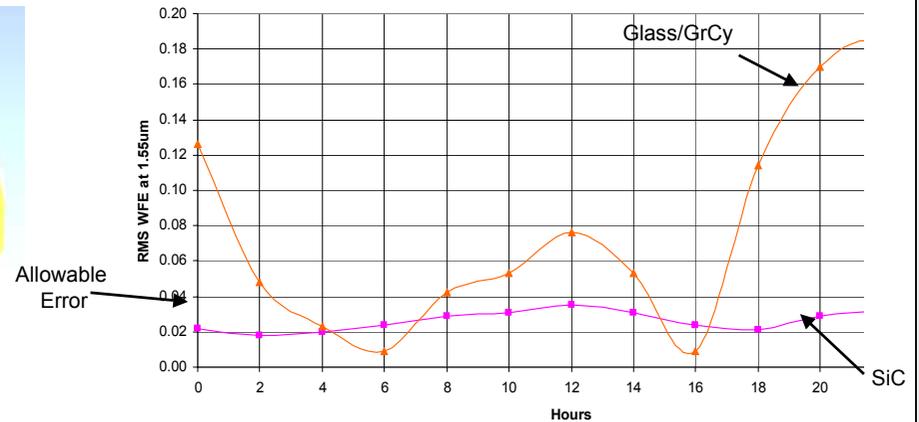
On Axis



Off Axis



## Direct Solar Loading on Telescope



## Applications

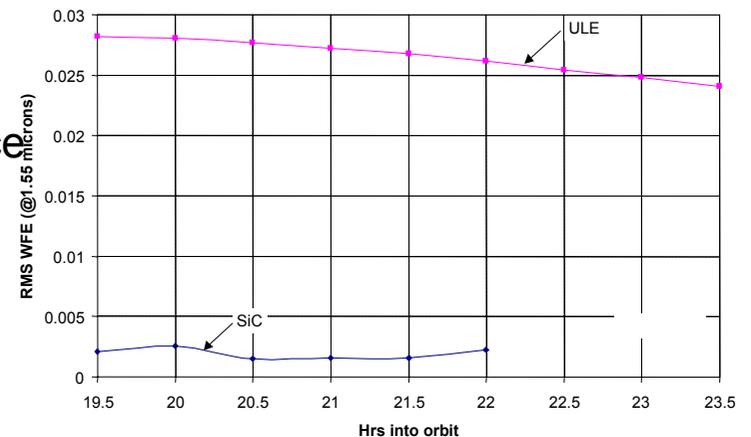
- GEO remote sensing
- LaserCOMM crosslinks for GEO & LEO

## Telescope Problem

- Sun in aperture causing solar induced performance degradation & system outages

## Sun on Primary Mirror

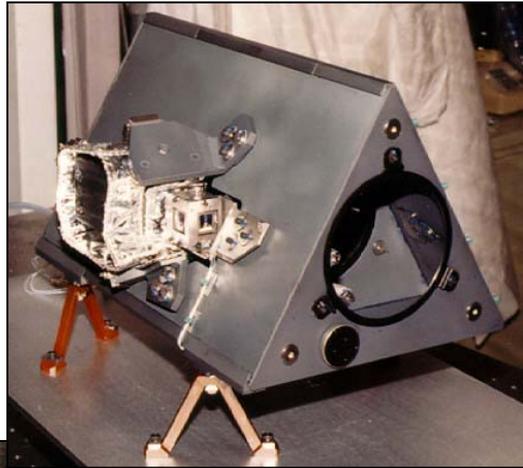
Transient Thermal Effects



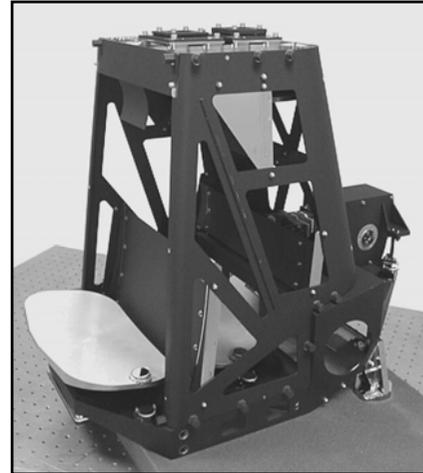
**SiC Telescope Can Maintain Visible Quality Performance with DIRECT Solar Loading; Only Possible Material Solution**

# SiC Demonstrated as a Critical Technology within NASA's New Millennium Flight Program

SiC MICAS instrument developed by SSG (NASA DS-1)



SiC ALI instrument developed by SSG (NASA EO-1)



Patricia Beauchamp of JPL holding the MICAS Instrumentation. The 1970s Voyager Instruments can be seen in the background

Advanced LandSat Imaging data obtained from ALI-EO-1 instrument



- SiC is one of several critical technologies required for a dramatic change in space based EO Instrumentation
- The MICAS instrument weights <7 kgs but performs all of the same functions as the voyager instruments, which weighed >100 kgs, while providing improved sensitivity